

10/568706

Atty. Dkt. No. 039262-0150

IAP20 Rec'd PGTWTO 17 FEB 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tadahiro OHMI, et al.
Title: VACUUM PROCESSING APPARATUS AND
VAPOR DEPOSITION APPARATUS
Appl. No.: Unassigned (US National Phase of
PCT/JP2004/012239)
Intl. Filing Date: 08/19/2004
Examiner: Unassigned
Art Unit: Unassigned

PRELIMINARY AMENDMENT UNDER 37 CFR 1.115

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to examination of the present Application, Applicant respectfully requests that the application be Currently Amended as follows:

Amendments to the Specification begin on page 2 of this document.

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this document.

Remarks/Arguments begin on page 9 of this document.

Please amend the application as follows: